

Application No. 10/643,682  
Response to Office Action

Customer No. 01933

Amendments to the Abstract:

Please replace the Abstract of the Disclosure with the following amended Abstract of the Disclosure::

ABSTRACT OF THE DISCLOSURE

A chemical treatment apparatus of this invention is an apparatus method by which a chromium metal film formed on a material to be subjected to film formation is etched into a predetermined pattern. This apparatus The method includes a cathode electrolysis reduction device for step comprising performing an electrolysis reduction treatment for [[the]] chromium a metal film as a cathode by using [[a]] one of an acidic reduction treatment solution containing chloride ions[], and an acid dip device for dipping the chromium film into an acidic radical and an alkaline reduction treatment solution after the electrolysis reduction treatment is performed by the cathode electrolysis reduction device, and an etching step.